APPLICATION DATA SHEET

Application Information:

Application Type:

Utility

Subject Matter:

Title:

Method of Dry Plasma Etching Semiconductor Materials

Attorney Docket Number: P1573 Request for Early Publication: No Request for Non-Publication: No

Suggested Drawing Figure:

Total Drawing Sheets: Small Entity:

4 No

Inventor Information:

Inventor Authority type: Primary Citizenship Country:

Status:

P.R. China Full Capacity

First Inventor

Given Name:

Jennifer

Middle Name/Initial:

Family Name:

Wang

City of Residence:

Redondo Beach

Country of Residence:

USA

Street address:

1800 S. Pacific Coast Hwy, Unit 44

City:

Redondo Beach

State or Province:

California

Postal or Zip Code:

90277

Correspondence Information:

Firm Name:

LaRiviere, Grubman & Payne, LLP

Street address:

P.O. Box 3140

City:

Monterey

State or Province:

California

Postal or Zip Code:

93942

Telephone:

(831) 649-8800

Fax:

(831) 649-8835

Representative Information:

Representative Customer Number: 24,394

LaRiviere, Grubman & Payne, LLP

Assignee Information

Assignee Name:

Northrop Grumman Space & Mission Systems Corporation Space Technology, One Space Park, Bldg. Street Address:

R11/2796BE

Redondo Beach City:

State or Province: California

Country: USA

Postal or Zip Code: 90278